

MetPrep Preparation Procedure – No 153



Reaction bonded Silicon Nitride + Yttria & Aluminium Nitride

	Surface	Abrasive	Pressure		Speed – Dir	Time
Primary Grinding Stage	Fixed Diamond	40 µm MB	Psi	N	500 – Comp	Until Planar
			5	25		

	Surface	Abrasive	Pressure		Speed – Dir	Time
Additional Grinding Stages	Abracloth	15 µm (WB) PCD Diamond	Psi	N	250 – Comp	5 mins
			5	25		
	Planocloth	3 µm (WB) PCD Diamond	5	25	250 – Comp	5 mins

	Surface	Abrasive	Pressure		Speed – Dir	Time
Polishing Stage	Planocloth	0.06 µm Silco	Psi	N	100 – Contra	8 mins
			5	25		